

ABSTRACT

An integrated inspection system adapted to inspect a substrate. A first inspection station performs a first inspection of the substrate at a first resolution, and identifies defect candidate sites. A controller determines position information associated with each of the identified defect candidate sites. A second inspection station performs a second inspection of the defect candidate sites at a second resolution, where the second resolution is higher than the first resolution. A substrate stage moves the substrate between the first inspection station and the second inspection station, and indexes the substrate under both the first inspection station and the second inspection station.

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